

#### ABSTRACT OF THE INVENTION

An aluminum material having, on the surface thereof, an AlN region which has enhanced film thickness, is uniform within the region and exhibits a high adhesion to a base material; and a method for producing the aluminum material, which comprises a step of providing an aluminum material comprising  $\text{CuAl}_2$ , and a step of subjecting said aluminum material to plasma nitriding, to thereby form the aluminum nitride (AlN) region on the surface of the aluminum material.